

IN THE CLAIMS

Please amend the claims as follows:

1. (original) A domain expansion storage medium in which a magnetic wall is displaced to thereby enlarge a magnetic domain in a readout layer so as to reproduce an information indicated by a magnetic domain in a storage layer, wherein a substrate of said storage medium has a locally modified surface structure or said storage layer has a locally modified magnetic property, arranged to define a predetermined shape of said magnetic domain, said predetermined shape having a curvature adapted to a predetermined thermal reading profile.
2. (original) A storage medium according to claim 1, wherein said magnetic domain has a crescent shape reversed with respect to a rotation direction of said storage medium, the curvature of the concave edge of said crescent shape substantially matching with the facing curvature of said predetermined thermal reading profile.
3. (currently amended) A medium according to claim 1 or 2, wherein said substrate has an injection moulded format.

4. (currently amended) A storage medium according to any one of the preceding claims claim 1, wherein said storage medium is a MAMMOS disc or a DWDD disc.

5. (original) A method of manufacturing a domain expansion storage medium, in which a magnetic wall is displaced to thereby enlarge a magnetic domain in a readout layer so as to reproduce an information indicated by a magnetic domain in a storage layer, said method comprising the step of locally processing the surface structure of a substrate of said storage medium or the magnetic properties of said storage layer so as to define a predetermined shape of said magnetic domain, said predetermined shape having a curvature adapted to a predetermined thermal reading profile.

6. (original) A method according to claim 5, wherein said magnetic domain is defined with a crescent shape reversed with respect to a rotation direction of said storage medium, so that the curvature of the concave edge of said crescent shape substantially matches with the facing curvature of said thermal reading profile.

7. (currently amended) A method according to claim 5 or 6, wherein the surface structure of said substrate is processed in said processing step.

8. (currently amended) A method according to ~~any one of claims 5~~
~~to 7~~claim 5, wherein said substrate is processed by an electron
beam recording method or a recording method adapted to induce a
localized difference in said magnetic properties.
9. (currently amended) A method according to ~~any one of claims 5~~
~~to 7~~claim 5, wherein said substrate is processed by using a stamper
obtained from an injection moulded master substrate.
10. (original) A method according to claim 9, wherein said master
substrate is mastered by an e-beam recording method.